

Attorney Docket No. 46884-5497	Application No.: 10/585,451
Applicant(s): Kazuhiro ATSUMI et al.	
Filing Date: July 7, 2006	Group Art Unit:

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Document Number	Date	Country	Class	Sub Class	Translation YES NO
JP 04-111800	Apr. 13, 1992	Japan			X
JP 07-040336	Feb. 10, 1995	Japan			X (abstract)
JP 10-163780	Jun. 19, 1998	Japan			X (abstract)

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

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<b>INFORMATION DISCLOSURE CITATION</b> (Use several sheets if necessary) Page 1 of 1 PTO Form 1449				Attorney Docket No. 46884-5497		Application No.: 10/585,451	
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	Document Number	Date	Country	Class	Sub Class	Translation YES NO	
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